

b) Amendments to the Specification:

Please amend paragraph [0008], bridging pages 2 and 3 as follows:

AI
--[0008] As an improvement for overcoming the problem mentioned above,
there is known a reactive sputtering process employing a plasma emission monitor
(abbreviated as "PEM" hereinafter) (S. Schiller, U. Heisig, Chr. Korndorfer, J. Strumpf, and V. Kirchhoff, "Progress in the Application of the Plasma Emission Monitor in Web Coating", [()]Proceedings of the 2nd International Conference on Vacuum Web Coating, Fort Lauderdale, Florida, USA, Oct. 1988).--
